



Inventor: Mathew S. Cooper
Physical Vapor Deposition Components and Methods of Formation
Assignee: Micron Technology, Inc.
Docket No. H0001190 (4016)

9/w.m.
5/20/03

INFORMATION DISCLOSURE STATEMENT

References – See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 12 May 2003 Attorney: RJL
James E. Lake
Reg. No. 44,854

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